Nexcope®

NX系列

Industrial inspection microscope

Suitable for large size samples

Check requirements

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NX Series

Industrial inspection microscope

Whether it is a very small sensor or a large wafer, or even an entire LCD screen, the NX series industrial inspection microscope can be used to observe it. With various sizes of loading platforms and a large range of movement, it is easy and fast to move and focus, and can quickly locate the sample range. It is an ideal tool for microscopic observation of large-area industrial samples.

Enables rapid positioning and imaging of very large samples

Built-in clutch platform handle

Microelectronics and semiconductor samples are often large in size, and ordinary metallographic microscope platforms cannot meet their observation needs. The NX series industrial inspection microscopes can be equipped with various platform-level platforms of different sizes.

The bracket has a large moving range and is easy and fast to move. It can realize fast and slow movement of the loading platform, and can quickly locate large-area samples.

It is an ideal tool for microscopic observation of large-area industrial samples.

Near-end design

The controls frequently used for microscopic observation are located on the front of the microscope (closest to the operator).

This allows you to operate the microscope faster and more conveniently when observing samples.

Erect image observation tube

Standard erect image observation tube, compared with the traditional inverted image tube, platform movement and eyepiece observation

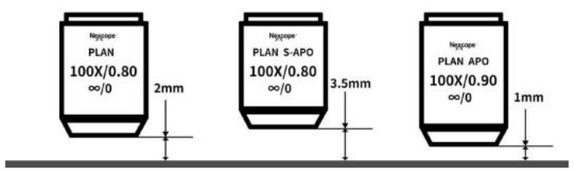
More synchronization.

A variety of objective lenses for you to choose

Adopt special objective lens with longer working distance to meet the imaging needs of industrial samples, multi-layer

The coating technology can compensate for spherical aberration and chromatic aberration from ultraviolet to near infrared.

Sharpness, clarity and color reproduction.



Multiple observation methods to meet various testing needs

The NX series industrial inspection microscopes can realize a variety of observation methods through modular combination: bright field, dark field, oblique illumination, polarized light, DIC, etc. *

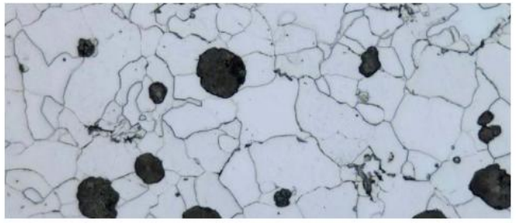
	Brightfield	Dark Field	DIC	Oblique lighting	Polarized
Falling Shot	O	O	O	O	O
transmission	O	-	-	-	-

* Functions of each model vary, please call for details

Bright field

NX1000 adopts the excellent NIS wireless telephoto optical system. The field of view is uniform, bright, and colorful.

High reduction degree. Suitable for observing opaque samples such as semiconductors.



Dark Field

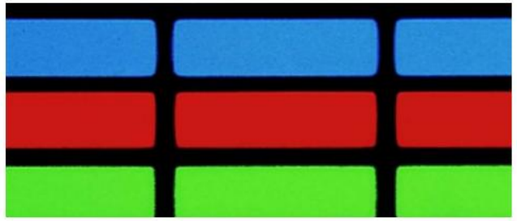
Bright dark field observation can be achieved, and defects such as small scratches can be detected with high sensitivity.

Suitable for surface testing of samples with high requirements.

Transmitted Brightfield

For transparent samples, such as FPD, optical components, etc., this can be achieved by projecting light condensers

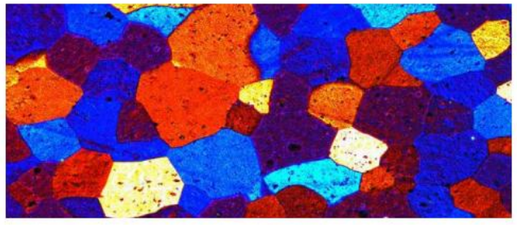
Bright field observation.



Polarized

This observation method is suitable for specimens with birefringence properties, such as metallographic structures, minerals, LCD

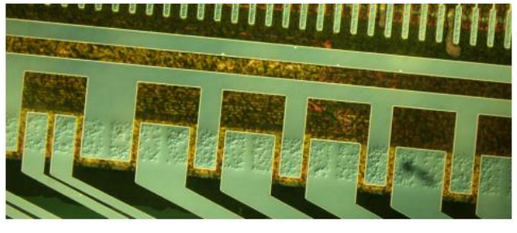
and semiconductor materials.



Epi-DIC

Used to observe small differences in precision molds.

Subtle height differences that are invisible to the naked eye are expressed in the form of relief and three-dimensional images.



NX2000

12-inch platform large travel industrial inspection

microscope for ÿ300mm wafers and 17-inch FPD samples

NX1000

12-inch platform industrial inspection

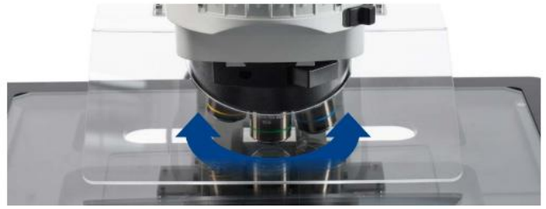
microscope for observation of ÿ300mm wafers and 17-inch FPD

Large sample space

Nexcope NX2000/NX1000 industrial inspection microscope has a large stage and a large moving range, mainly used for precision observation of 12-inch or 300 mm diameter samples. NX2000 can achieve a maximum Z-axis travel of 200mm. The fine-tuning handle and the moving handle with built-in clutch can quickly position large-area samples. The easy-to-change stage plug-in provides a wide variety of stage plug-ins for you to choose from, no matter what type and size of sample you want to inspect.

Built-in control panel for electric control

By setting specific buttons to correspond to specific objective lenses, you can easily change the magnification with just a touch. It can also remember the lighting brightness when using each objective lens, and automatically adjust the light intensity when switching between different objective lenses to reduce visual fatigue. The NX2000 can intelligently adjust the focusing speed of the objective turret through the rotation speed and focusing distance of the focus handwheel, so that focusing is faster and more accurate.



Sample protection mechanism

The NX series has a Z-axis lock function to prevent the objective lens from touching the sample, protecting the microscope and precious samples. The NX2000 has a Z-axis escape and return function, making sample replacement easier and safer.

NX800

8-inch platform industrial inspection microscope

For observation of ÿ200mm wafers

NX600

6-inch platform industrial inspection microscope

For observation of ÿ150mm wafers

The right platform size

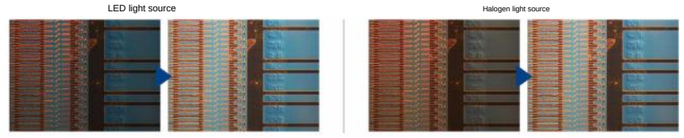
The NX800 and NX600 are equipped with 8-inch and 6-inch platforms respectively, with a wide variety of stage plug-ins for you to choose from, suitable for wafers of 200mm and below and larger FPD samples.

Adjustable handle and mobile handle with built-in clutch facilitate quick positioning of samples.

Provides true color imaging

The NX Series is available with an optional LED light source. LED lighting provides a constant color temperature and true

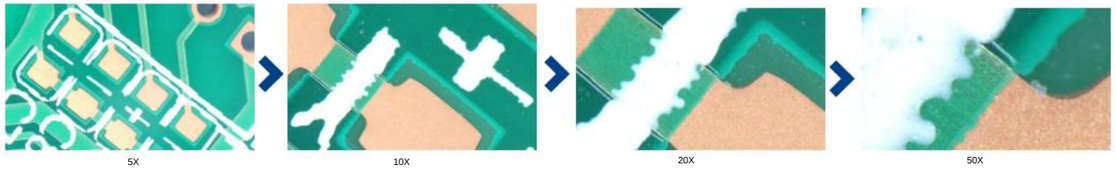
Color imaging. LED has a long service life, low power consumption, and easy maintenance, making it an ideal microscope light source.



Color changes in microscopic imaging under different light sources and brightness

Brightness memory function

It can memorize the lighting brightness when using each objective lens. When different objective lenses are switched, the light intensity is automatically adjusted to reduce visual fatigue and improve work efficiency.



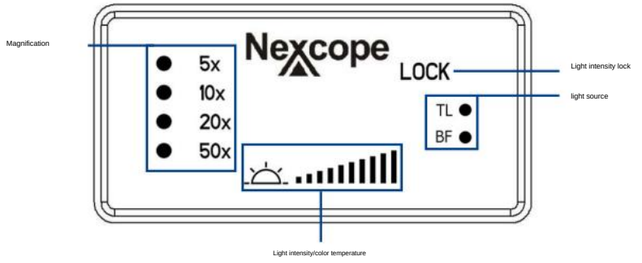
Brightness of images at different magnifications

Microscope status display function

* This function is only available for NX600

The LCD screen on the front of the microscope can display the status of the microscope, including

Including magnification, light intensity, color temperature, light source status, etc.



Breaking through the conventional light source conversion mode

Both the transmitted light source and the reflected light source are linked to the multi-function turntable, which is different from the conventional buttons.

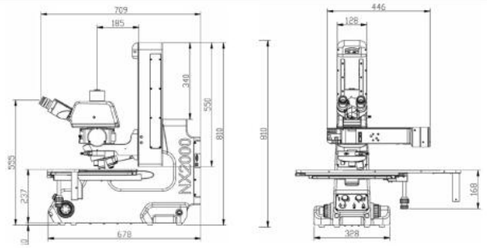
Compared with the key switch button, the light source conversion is more convenient and more suitable for beginners.

scholar.

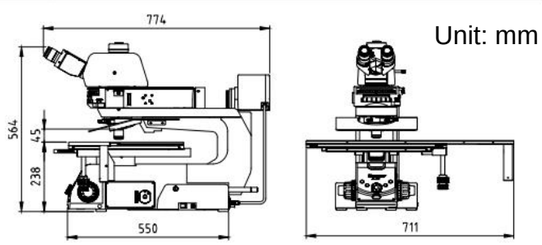
NX2000/NX1000 Industrial Inspection Microscope Configuration

	NX2000	NX1000
Optical system	Infinity optical system	
eyepiece	10X large field eyepiece, linear field of view ý22mm, high eye point, adjustable diopter	
Focusing system	Coaxial intelligent variable speed focusing for coarse and fine movement ， Focusing range 200mm Z-axis lock function, escape and return function	Low hand position coaxial focusing mechanism ， Focusing range 32mm The right hand has a Z-axis lock function
Epi-illumination	5W LED light, adjustable brightness, brightness memory	12V, 100W halogen lamp, brightness adjustable
Transmitted illumination	5W LED light, adjustable brightness, brightness memory	LED-40A Cold Light Source
Eyepiece tube	Ergonomic hinged erect trinocular observation tube ， Eyepiece/Port: 100/0, 0/100, Depth Angle: 0-30 degrees, Interpupillary Distance Adjustment Range: 47-78mm	
Nosepiece	Motorized six-position bright-field and dark-field converter with DIC slot	
Objective	Infinity Plan Semi-apochromatic/Apochromatic Brightfield and Darkfield Metallographic Objectives	
Stage	Clutch stage 14" x 12", travel: 356 x 305 mm, for 300 mm wafers, with sample holder	
Condenser	Condenser for transmitted illumination	
Observation Methods	Bright field, dark field, DIC, simple polarization	

Unit: mm



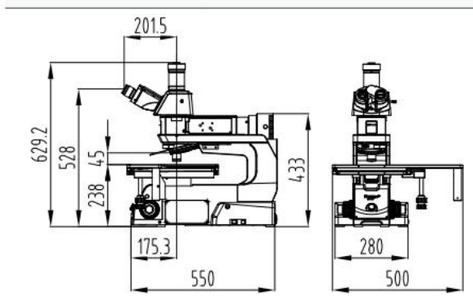
Nexcope NX2000 Microscope Dimensions



Nexcope NX1000 Microscope Dimensions

NX800/NX600 Industrial Inspection Microscope Configuration

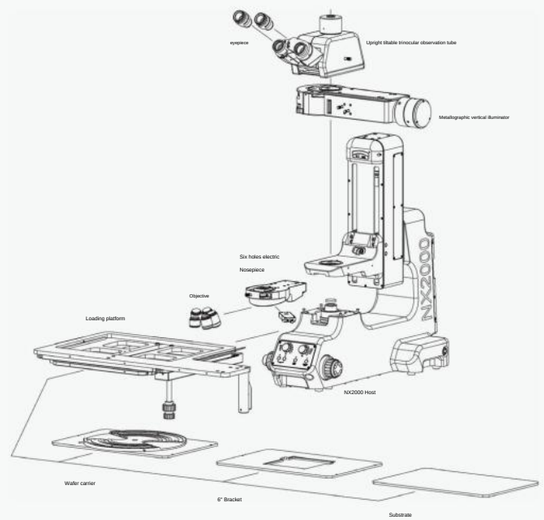
	NX800	NX600
Optical system	Infinity optical system	
eyepiece	10X large field eyepiece, linear field of view ý25mm, high eye point, adjustable diopter	
Focusing system	Low hand position coaxial focusing mechanism, focusing range 32mm	Low hand position coaxial focusing mechanism, focusing range 32mm
Epi-illumination	5W LED light, adjustable brightness, brightness memory	3W LED light, adjustable brightness, brightness memory
Transmitted Illumination	10W LED light, adjustable brightness, brightness memory	3W LED light, adjustable brightness, brightness memory
Eyepiece tube	Hinged erect trinocular observation tube, eyepiece/port: 100/0, 0/100, depression angle: 30 degrees, interpupillary distance adjustment range: 47-78mm	
Nosepiece	Five-hole bright-dark field converter	Coded six-hole bright-field and dark-field converter
Objective	Infinity Plan Brightfield and Darkfield Metallographic Objectives	
Stage	8" clutch platform, travel: 210×210 mm For 200 mm wafers, with sample holder	6" clutch platform, travel: 160×160mm For 150 mm wafers, with sample holder
Condenser	Condenser for transmitted illumination	
Observation Methods	Bright field, dark field, DIC, simple polarization	



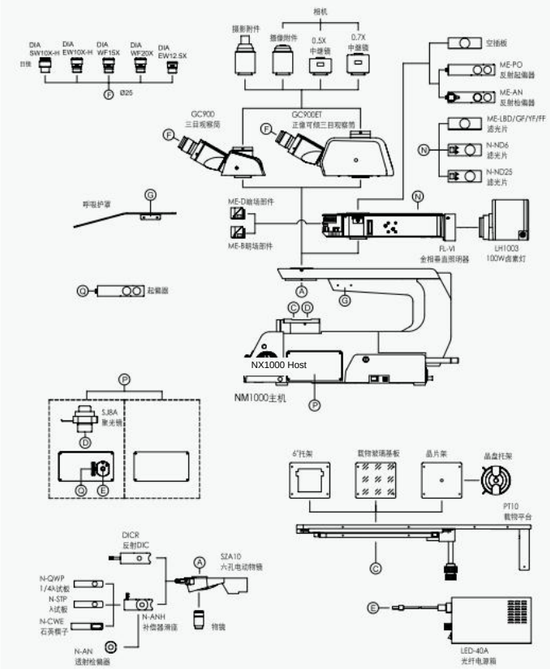
Nexcope NX800 Microscope Dimensions

System Diagram

For Nexcope NX2000 microscope



For Nexcope NX1000 microscope



For Nexcope NX800 microscope